

35673 U.S. PAT.
10/003287
12/06/01

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10003287	FILING DATE 12/06/2001	CLASS 433	SUBCLASS 2942	GAU 2942	EXAMINER 10003287
**APPLICANTS: Kang Sang;					
**CONTINUING DATA VERIFIED: SPM NONE					
** FOREIGN APPLICATIONS VERIFIED: REPUBLIC OF KOREA 2001-54510 09/05/2001 SKM					
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>			
Foreign priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no Verified and Acknowledged Examiners's initials SKM SKM				ATTORNEY DOCKET NO 10729-P67237US0	
TITLE : Method of fabricating an exposure mask for semiconductor manufacture <small>U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)</small>					

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NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drawg.	Figs. Drawg. Print Fig.
<input type="checkbox"/> TERMINAL DISCLAIMER		Application Examiner	
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